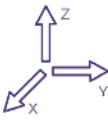


S, SH & SD Series

Compact Design, Capacitive Sensor Close-loop Control

Multi Degrees of Freedom, Travel Range up to 500 μm , High Dynamic and High Load optional

Standard

1 Axis		S100.X.C 100 μm	S300.X.C 300 μm	S500.X.C 500 μm
		S100.Z.C 100 μm	S300.Z.C 300 μm	
2 Axes		S100.XY.C 100 μm , 100 μm	S300.XY.C 300 μm , 300 μm	S500.XY.C 500 μm , 500 μm
3 Axes		S100.XYZ.C 100 μm , 100 μm , 100 μm	S200.XYZ.C 200 μm , 200 μm , 200 μm	

* Non-magnetic, Ultra High Vacuum Versions available

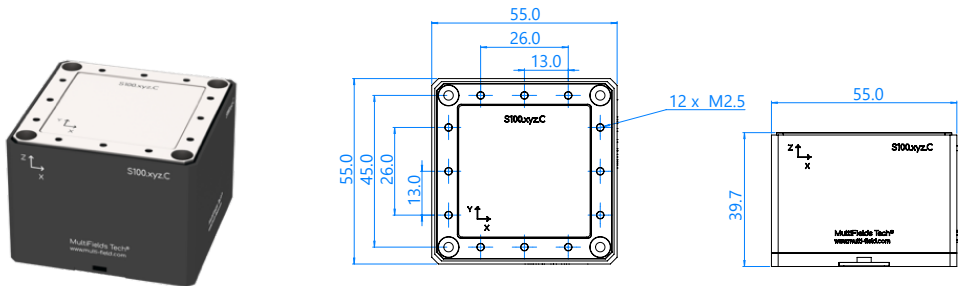


XY/XYZ Piezo Scanner — S100.XY/XYZ, S200.XY/XYZ

Compact XYZ Stack System

- Feature
- Piezo Stack Driving
 - Direct Metrology
 - Flexure Guiding
 - Sub-nanometer Resolution
 - CAP Sensor, Close-loop Control
 - Compact Serial Structure

➤ Photo & Drawing



➤ Specification

S100.XY.C

S200.XY.C

S100.XYZ.C

S200.XYZ.C

1	Optional	.NM, Non-magnetic; .HV, High Vacuum Version; .UHV, Ultra High Vacuum Version;			
2	Motion Direction	X, Y		X, Y, Z	
3	Footprint × Height	55 × 55 × 27 mm	55 × 55 × 30 mm	55 × 55 × 40 mm	55 × 55 × 45 mm
4	Material	Aluminum, Stainless Steel			
5	Travel Range (Open-loop)	120 × 120 μm	240 × 240 μm	120 × 120 × 120 μm	240 × 240 × 240 μm
6	Travel Range (Close-loop)	100 × 100 μm	200 × 200 μm	100 × 100 × 100 μm	200 × 200 × 200 μm
7	Resolution (Open-loop)	0.2 nm	0.4 nm	0.2 nm	0.4 nm
8	Resolution (Close-loop)	1 nm	1.5 nm	1 nm	1.5 nm
9	Linearity	0.03%			
10	Resonant Frequency (X/Y/Z no load)	400 / 350 / – Hz	300 / 250 / – Hz	400 / 350 / 300 Hz	300 / 250 / 200 Hz
11	Stiffness	0.5 N/μm	0.25 N/μm	0.5 N/μm	0.25 N/μm
12	Sensor Type	Capacitive			
13	Driving Voltage	Max. 150 V			
14	Working Temperature	15 ~ 40 °C			
15	Cable	D-Sub 3W3			
16	Controller	MC-Archimedes.N			

* For detail drawing and 3D model please contact us.

Carrier.S Series

Versatile, High Performance

Multi Degrees of Freedom, Parallel Metrology with Capacitive Sensor, Parallel Kinematic

Travel Range – 100 μm

1 Axis



Carrier.S100.Z.C

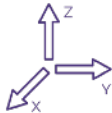
100 μm

2 Axes



Carrier.S100.XY.C

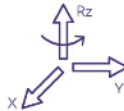
100 μm , 100 μm



Carrier.S100.XYZ.C

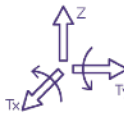
100 μm , 100 μm , 100 μm

3 Axes



Carrier.S100.XYRz.C

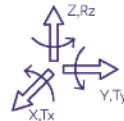
100 μm , 100 μm , ± 1 mrad



Carrier.S100.ZTxTy.C

100 μm , ± 1 mrad, ± 1 mrad

6 Axes



Carrier.S100.XYZTxTyRz.C

100 μm , 100 μm , 100 μm , ± 1 mrad,
 ± 1 mrad, ± 1 mrad

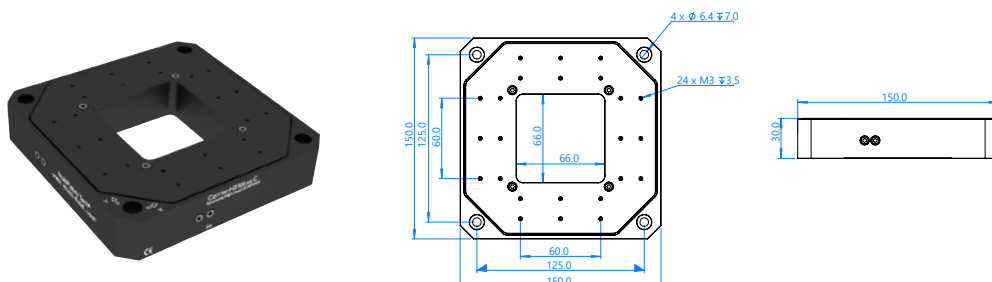
* Non-magnetic, Ultra High Vacuum Versions available

XY Piezo Scanner — Carrier.S100/200.XY.C

Versatile, High Performance, Clear Aperture, XY Motion

- ➔ Feature
 - Piezo Stack Driving
 - Flexure Guiding
 - CAP Sensor, Close-loop Control
 - Parallel Metrology
 - Sub-nanometer Resolution

➔ Photo & Drawing



➔ Specification

Carrier.S100.XY.C

Carrier.S200.XY.C

1	Optional	.NM, Non-magnetic; .HV, High Vacuum Version; .UHV, Ultra High Vacuum Version;	
2	Motion Direction	XY	
3	Footprint x Height	150 x 150 x 30 mm	
4	Material	Aluminum, Stainless Steel	
5	Travel Range (Close-loop XY)	100 x 100 µm	200 x 200 µm
6	Aperture	66 x 66 mm	
7	Linearity	0.03%	
8	Resolution (Close-loop / Open-loop)	1 nm / 0.2 nm	2 nm / 0.4 nm
9	Repeatability	10 nm	10 nm
10	Stiffness	2 N/µm	1 N/µm
11	Resonant Frequency (no load / 2.5 kg)	420 / 130 Hz	340 / 100 Hz
12	Max. Payload	5 kg	
13	Sensor Type	Capacitive	
14	Driving Voltage	Max. 150 V	
15	Working Temperature	15 ~ 40 °C	
16	Controller	MC-Archimedes.N	

* For detail drawing and 3D model please contact us.